Sheet U.S. Dept. of Commerce Attorney Docket No.: Serial No.: 09/960,479 Patent and Trademark Office Applicant: Tokuda, Mitsuo, et al. INFORMATION DISCLOSURE CITATION (Use several sheets if necessary) Filing Date: September 24, 2001 Group: U.S. PATENT DOCUMENTS FILING DATE Initial\* REF **DOCUMENT NUMBER** DATE IF APPROPRIATE CLASS NAME CLASS 6 10/09/84 Reid, et al. AA 6 8 250 310 AB 5 2 0 5 5 2 12/14/93 Ohnishi, et al. 250 307 **FOREIGN PATENT DOCUMENTS** SUB-TRANSLATION **DOCUMENT NUMBER** DATE COUNTRY CLASS **CLASS** YES NO JH 07/21/98 **EU** Application AC 0 2 **G01N** 1/28 X AD ΑE OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.) Ohnishi, T., et al., "A new focused-ion-beam microsampling technique for TEM observation of site-specific areas." ISTFA '99. Proceedings of the 25<sup>th</sup> International Symposium for Testing AF and Failure Analysis. ASM Int. 1999, pp. 449-53 (14-18 Nov. 1999). Materials Parks, OH, USA Pawley, James B., "A Dual Needle Piezoelectric Micromanipulator for the Scanning Electron Microscope." The Review of Scientific Instruments, Vol. 43, No. 4, April 1972. JIL AG AH **EXAMINER** DATE CONSIDERED

\*EXAMMER: Initial if references considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in

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